

Notice of References Cited

Application/Control No.

10/701,496

Applicant(s)/Patent Under

Reexamination

TOSAKI ET AL.

Examiner

ANISH DESAI

Art Unit

1794

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*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-6,518,343 B1	02-2003	Lucast et al.	524/276
	B	US-			
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	D	US-			
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	F	US-			
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	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Istvan Benedek and Luc J. Heymans, "Pressure-Sensitive Adhesive Technology", Marcel Dekker Inc., Chapter 8, page 412, 1997.
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a))
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